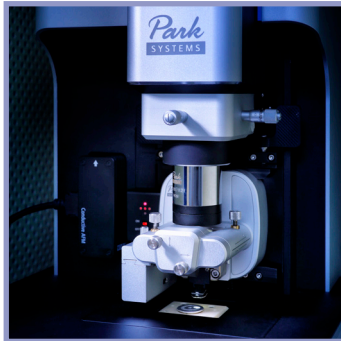


ATOMIC FORCE MICROSCOPY ANALYSIS SERVICE

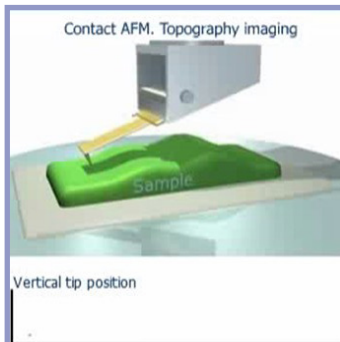
- SINGLE TRANSISTOR LOCALIZATION
- LOCAL I/V CURVE TRACING
- SURFACE ROUGHNESS MEASUREMENT
- TRUE NON-CONTACT AFM
- CONDUCTIVE AFM

ATOMIC FORCE MICROSCOPY ANALYSIS SERVICE



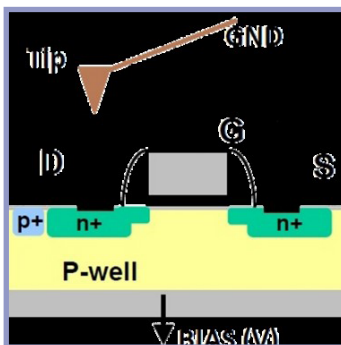
PARK NX10 FEATURES

- High speed 24-bit digital electronics
- 100 μm x 100 μm XY scan area
- 15 m Z-direction scan range
- I/V curve measurement
- Maximum resolution of 0.05 nm



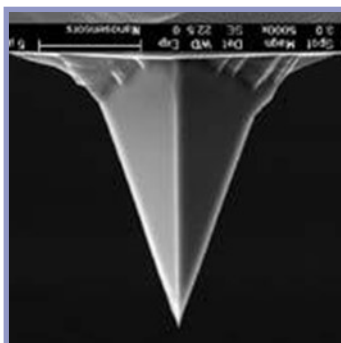
SCANNING MODES

- True Non-Contact AFM
- Basic Contact AFM
- Intermitted (Tapping) AFM



MEASUREMENT MODES

- Surface Morphology
- Conductive AFM (C-AFM)
- Electrostatic Force Microscopy (EFM)
- Force Modulation Microscopy (FMM)
- Lateral Force Microscopy (LFM)
- Magnetic Force Microscopy (MFM)
- Scanning Tunneling Microscopy (STM)



APPLICATION EXAMPLES

- Gate oxide breakdown localization
- Open via or -plug detection
- Molten via or -plug detection
- Surface roughness measurement
- Transistor I/V measurement